

## OUR SERVICE

### ELECTRONICS CONDITION MONITORING LAB

- Excitation vibration tests for electronic modules (sinus, white noise, shock), combined with humidity and temperature stresses
- Contactless vibration testing for design optimization, weakness analysis, and fault detection
- HALT testing to establish failure limits for temperature, extreme temperature variation, and vibration
- Level drop tester for shock tests and continuous monitoring of max acceleration, impulse duration, and impulse characteristics

### POWERLAB FOR POWER ELECTRONICS

- Active and passive load alternation tests for power semiconductors in a range of form factors and technologies
- Calibration of the barrier layer temperature and monitoring of parameters for every sample
- Thermographic monitoring during active testing

### THERMAL AND ENVIRONMENTAL ANALYSIS LAB

- Heat flow optimization for heat sinks and thermal distributors via wind tunnel or dynamic fluid simulation
- Component and system analysis to establish surface temperatures and thermal resistance
- Identification of the thermal resistance and heat conductivity of Thermal Interface Materials

## GET IN CONTACT

### Fraunhofer Institute for Reliability and Microintegration IZM

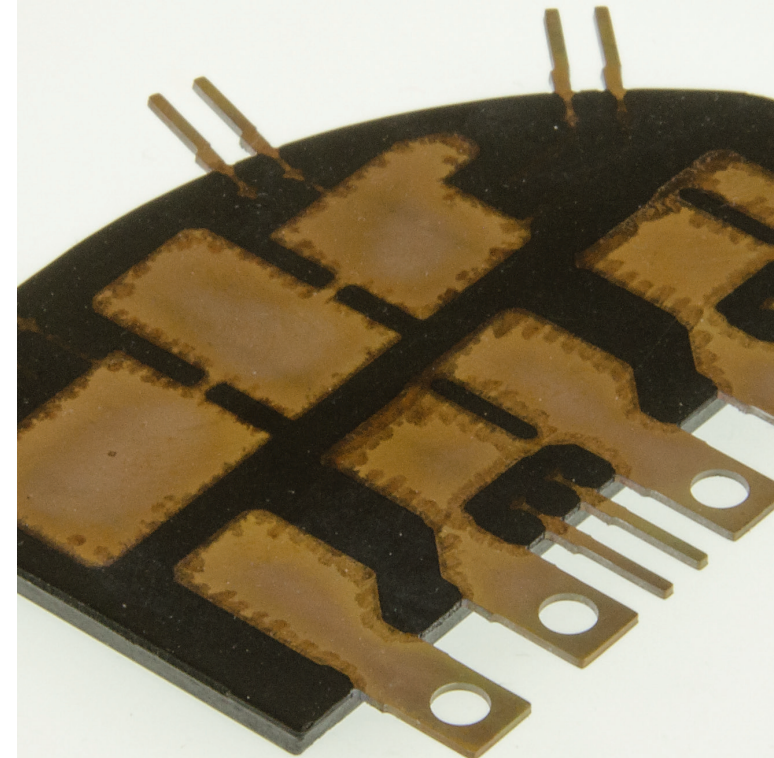
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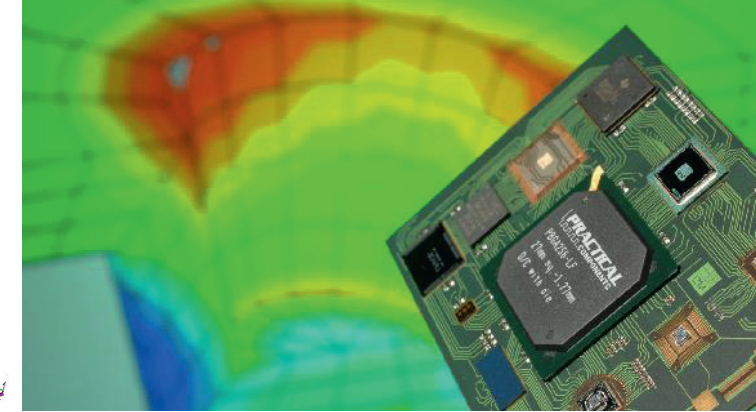
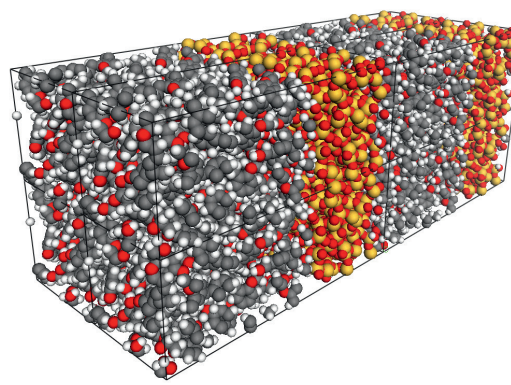
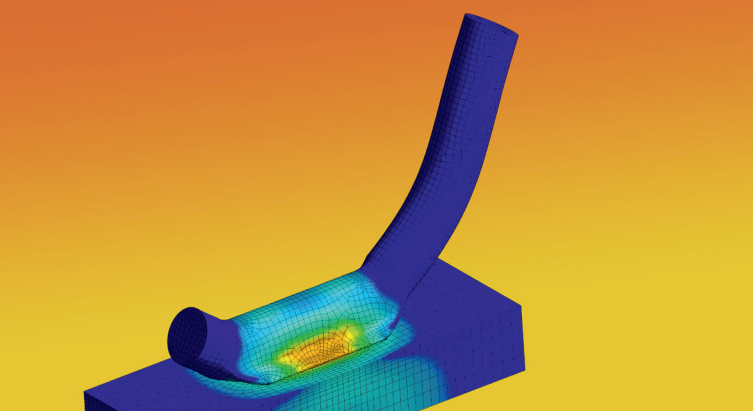
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## STRESS-MEASUREMENT FOR MICROSYSTEMS

CMOS Stress-Measurement-System quantifies loads  
during production and operation





## PROBLEM

Assembling and packaging processes in micro system technology need a high degree of process know-how in order to minimize negative mechanical stress effects on micro electronic sensors and systems.

MEMS-sensors or multi chip modules are exposed to high thermal and thermo mechanical loads during interconnection and packaging phases and during operation time. Resulting mechanical forces acting on the systems can cause changes in component feature and functionality.

## SOLUTION

The Fraunhofer IZM provides the service of stress-measurement for applications in development, assembly and quality management using a calibrated stress measuring system, which was optimized within the BMBF funded project "iForceSens".

The test chip will replace the micro system or other electronic parts and will pass through the same production and testing steps as the system under inspection, recording all emerging stress actions.

On basis of the CMOS technology, piezoresistive structures detect shear stress, temperature and the two normal stress components on the chip surface.

The resulting understanding of the failure mechanism supplies important indicators for product- and process optimization.

## CHARACTERISTICS

- **Stress distribution** ( $\tau_{xy}$ ,  $\sigma_{xx}$ ,  $\sigma_{yy}$ ) and **temperature** measurement integrated on one silicon chip
- **Four chip variants** with dimensions of: 1.1x1.1 mm<sup>2</sup>, 1.7x1.7 mm<sup>2</sup>, 1.7x2.8 mm<sup>2</sup>, 1.9x3.5 mm<sup>2</sup> chip thickness: 10 µm to 725 µm (backside chip thinning)
- **Four electrical connections** per chip (multiplexer): wire bonding: AlSiCu - metallization  
flip chip: UBM-metallization possible
- Stress resolution
  - induced difference stress: +/- 1.2%
  - induced shear stress: +/- 4.5%
  - single normal stress components: +/- 13% of total stress
- Time resolution: 50 ms for single cell readout
- Pitch of measuring cells: 260 µm
- Lateral interpolated space resolution: 50 µm
- Operation temperature: -40°C ... +180°C

## APPLICATION FIELD

- **Processes of assembly and interconnection**  
Die- / wire bonding, flip chip-assembly / underfilling / glob top, transfer molding, injection molding  
Optimization of encapsulation processes:  
concerning minimal induced stress and thermal stress postcuring.
- **Stress measurement at final assembly**  
MID, chip on board, embedding thinned chips in PCB...

## Quality and reliability tests

detailed insight in stress changes and correlation with failure mechanism (delamination, cracks, moisturized swelling...)

## ADDITIONAL SERVICE

- Assembly and interconnection technology
- Encapsulation technology: transfer molding, injection molding, hotmelt, vacuum casting
- Qualification- and reliability tests
- Failure analysis: X-ray, ultrasonics, metallography, SEM
- Thermo- mechanical simulation
- Simulation and analysis of encapsulation process

